Amendment to the Claims:

This listing of claims will replace all prior listing of claims in this application.

Listing of Claims:

CLAIMS

1. (Currently amended) An ECR plasma chamber (1) comprising:

an enclosure immersed in a magnetic configuration resulting from the superposition of two magnetic fields, one an axial magnetic field and the other a radial magnetic field, wherein the configuration of the electron trajectories depends on said the magnetic configuration[[,]]; and

characterized in that it comprises at least one moderator (100) whose having a position and shape are chosen as a function of said in relation to the magnetic configuration so such that said the at least one moderator (100) constitutes an obstacle to electrons whose energy is greater than a predetermined energy.

- 2. (Currently amended) The ECR plasma chamber according to claim 1, characterized in that wherein the position and number of said the at least one moderator moderators (100) within the magnetic configuration are chosen as a function of relates to the energy and the number of electrons to which an obstacle is required.
- 3. (Currently amended) The ECR plasma chamber according to claim 1 or claim 2, characterized in that the materials constituting wherein the materials of construction of the at least one moderators (100) are chosen as a function of their aptitude to moderator comprises materials that produce secondary electrons when they are subjected to collisions with high-energy electrons.
- 4. (Currently amended) The ECR plasma chamber according to any one of the preceding claims claim 1, characterized in that wherein the radial magnetic field has includes 2n poles and the at least one moderator (100) has includes n active portions (7) each of which is placed in a respective one of the n branches formed by the electron trajectories.

- 5. (Currently amended) The ECR plasma chamber according to any one of the preceding claims claim 1, characterized in that said wherein the at least one moderator (100) comprises at least one active portion (7) and a ring (6) encircling the plasma.
- 6. (Currently amended) The ECR plasma chamber according to claim 5, characterized in that said wherein the active portion (7) takes the form of comprises a cylindrical rod placed radially located in a transverse plane of the plasma chamber (1), wherein with ene a first end of the rod pointing points toward the a central region (3) of the plasma chamber (1) and the other a second end of the rod is fixed to said the ring (6).
- 7. (Currently amended) <u>The ECR plasma chamber according to claim 5, characterized in that said wherein the at least one active portion (7) is mounted at the end of a support rod, and wherein the support rod which is itself fixed to said the ring (6).</u>
- 8. (Currently amended) The ECR plasma chamber according to any one of claims 1 to 7 claim 1, characterized in that wherein at least a portion of the at least one moderator (100) has comprises a metal parts structure.
- 9. (Currently amended) <u>The ECR plasma chamber according to any one of claims 1 to 7 claim 1</u>, characterized in that wherein at least a portion of the at least one moderator (100) has comprises a ceramic parts structure.
- 10. (Currently amended) An ECR ion source comprising an ECR plasma chamber according to any one of claims 1 to 9 claim 1.
- 11. (Currently amended) An ECR plasma machine comprising an ECR plasma chamber according to any one of claims 1 to 9 claim 1.